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Appendix

Publications Arising From this Thesis

Patent

1. L.C. Zhang, B. Oliver, **Y. Chen**, and J.A. Arsecularatne, Method and apparatus for polishing diamond and diamond composites, Application Number 2006903375, Australian Patent Office, Jun 2006

Journal Papers

2. **Y. Chen**, L.C. Zhang, J.A. Arsecularatne and C. Montross, Polishing of polycrystalline diamond by the technique of dynamic friction, part 1: Prediction of the interface temperature rise. *International Journal of Machine Tools and Manufacture*, 46(2006) 580-587.
3. **Y. Chen**, L.C. Zhang and J.A. Arsecularatne, Polishing of polycrystalline diamond by the technique of dynamic friction, Part 2: material removal mechanism, *International Journal of Machine Tools and Manufacture*, 47 (2007) 1615-1624
4. **Y. Chen**, L.C. Zhang, J.A. Arsecularatne and I. Zarudi, Polishing of Polycrystalline Diamond by the Technique of Dynamic Friction, Part 3: Mechanism Exploration through Debris Analysis, *International Journal of Machine Tools and Manufacture*, submitted 2006, in press. (Available online 10 July 2007).
5. **Y. Chen**, L.C. Zhang and J.A. Arsecularatne, Optical surface finish of PCD composites by dynamic friction polishing, *Key Engineering Materials*, in press.

6. **Y. Chen**, L.C. Zhang, and J.A. Arsecularatne, Polishing of Diamond Composite Cutting Tools. *International Journal of Surface Science and Engineering*, (2007), (submitted).

Conference Papers

7. **Y. Chen**, L.C. Zhang and J.A. Arsecularatne, Optical surface finish of PCD composites by dynamic friction polishing, Proc. of the APCOM 2007, the first Asia Pacific Conference on Optics Manufacture, Hong Kong, 11-13 Jan 2007
8. **Y. Chen**, L.C. Zhang and J.A. Arsecularatne, Material removal mechanism in dynamic friction polishing of PCD. Proc. of the ICPMT2006, 8th International Conference on Progress of Machining Technology, Matsue, Shimane, Japan 7-12 Nov 2006 (received best paper award)
9. **Y. Chen**, L.C. Zhang, J.A. Arsecularatne and C. Montross, Estimation of the interface temperature rise for polishing PCD compacts. Proc. of the 2nd JSME/ASME International Conference on Materials and Processing 2005 (13th JSME Materials and Processing Conference), Seattle, USA 19-22 June 2005
10. **Y. Chen**, L.C. Zhang and J.A. Arsecularatne, Temperature Measurement and Characterisation for Nano-polishing of PCD composites. 8th International Symposium on Measurement Technology and Intelligent Instruments (ISMTII2007), Sendai, Japan, 25-27 September 2007.